

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MEHRDAD NIKOONAHAD ET AL.
Title: SCANNING SYSTEM FOR INSPECTION ANOMALIES ON SURFACES
Application No.: 10/666,120 Filing Date: September 19, 2003
Examiner: Unknown Group Art Unit: 2877
Docket No.: TNCR.001US4 Conf. No.: 8430

Certificate of Mailing Under 37 CFR 1.8

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Signature Eileen Bous

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicants call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application.

Copies of the documents listed on the accompanying Form PTO-1449 and Form PTO-892 that are not enclosed were previously submitted in Application No. 09/954,287 from which this Application claims an earlier effective filing date.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or

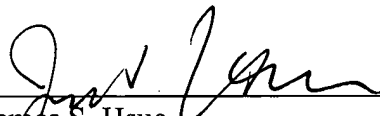
Attorney Docket No.: TNCR.001US4

Application No.: 10/666,120

(3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

This information disclosure statement is submitted under 37 C.F.R. § 1.97(b) and consequently no fee should be required. The Commissioner is authorized, however, to charge any fee that may be required, or to credit any overpayment, against Deposit Account No. 502664. This form is being submitted in duplicate.

Respectfully submitted,


James S. Hsue
Reg. No. 29,545

2/11/04
Date

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Erleen Bomer
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Commissioner for Patents
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Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, Applicants wish to call the following documents (copies enclosed) to the attention of the Examiner for the above-identified patent application.

A form PTO-1449 listing these documents are enclosed.

Citation of the above documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;

2. a representation that a search has been made, a representation that a search has been made, (other than as indicated by any cited document); or

3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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James S. Hsue
Reg. No. 29,545

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U.S. Department of Commerce, Patent and Trademark				Atty. Docket No.		Application No.		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				TNCR.001US4		10/666,120		
				Applicant(s)		Conf. No.		
				Nikoonahad et al.		8430		
				Filing Date		Group		
				9/19/03		2877		
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
U.S. Published Patent Application Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
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							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	1	Chang, "Acoustoopic Devices and Applications," <i>IEEE Transactions on Sonics and Ultrasonics</i> , Vol. Su-23, No. 1, January 1976, pp. 1-22.						
	2	Dickson, "Optical Considerations for an Acoustooptic Deflector," <i>Applied Optics</i> , Vol. II, No. 10, Oct. 1972, pp. 2196-2202.						
	3	Young, Jr. et al., "Design Considerations for Acousto-Optic Devices," <i>Proceedings of IEEE</i> , Vol. 69, January 1981, pp. 54-64.						
	4	Uchida et al., "Acoustooptic Deflection Materials and Techniques," <i>Proceedings of the IEEE</i> , Vol. 61, No. 8, August 1973, pp. 1073-1092.						
	5	Randolph et al., "Modulation Transfer Characteristics of an Acoustooptic Deflector," <i>Applied Optics</i> , Vol. 10, No. 6, June 1971, pp. 1383-1385.						
	6	Grossman et al., "High Speed Laser Facsimile Scanner," <i>SPIE, Laser Recording and Information Handling</i> , Vol. 200, 1979, pp. 8-15.						
	7	Merry, "High Resolution Acoustooptic Deflector Demonstrated in a Laser Scanner," pp. 32-34.						
	8	"All About Bragg Angle Errors in Acousto-Optic Modulators and Deflectors," <i>ISOMET</i> , May 1993, pp. 1-23.						
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	10	Alcousis-Optic Deflectors," <i>ISOMET</i> , pp. 1-9
Examiner	FEB 13 2004	Date Considered
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.		

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Atty Docket No.

Serial No.

TNCR.001US3

09/954,287

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant(s)

(Use several sheets if necessary)

MEHRDAD NIKOONAHAD ET AL.

Filing Date

Group

September 11, 2001

2877

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	A1	4,794,264	12/27/98	Quackenbos et al.	250	563	
	A2	5,888,710	03/30/99	Adachi et al.	430	523	
	A3	5,903,342	05/11/99	Yatsugake et al.	356	237.4	
	A4	6,081,325	06/27/00	Leslie et al.	356	237.2	
	A5	6,292,259	09/18/01	Fossey et al.	356	237.2	
	A6						
	A7						
	A8						
	A9						
	A10						
	A11						

Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	B1	63-284455	11/21/88	Japan			Yes	
	B2	H5-332946	12/17/93	Japan			Yes	
	B3							
	B4							
	B5							

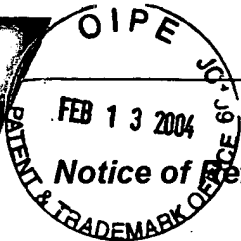
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C1	"Discrete Sources Method For The Silicon Wafers Defect Discrimination," Yuri Eremin and N. Orlov, <i>J. 12th Annual Review of Progress in Applied Computational Electromagnetics</i> , March 18-22, 1996, pp. 758-763
C2	"Determination of COP Distribution After SC1 Cleaning By A Laser Particle Counter," T. Fujise, et al., <i>Optical Characterization Techniques For High-Performance Microelectronic Device Manufacturing III</i> , SPIE Proc. Vol. 2877, Oct. 16, 19978, pp. 16-25
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Notice of References Cited

Application/Control No.

09/954,287

Applicant(s)/Patent Under
Reexamination
NIKOONAHAD ET AL.

Examiner

Richard A Rosenberger

Art Unit

2877

Page 1 of 1

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	A	US-5,125,741	06-1992	Okada et al.	356/237.2
	B	US-6,118,525	09-2000	Fossey et al.	356/237.2
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

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M-10575-3C US

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	A1	3,851,951	12/1974	Eveleth		
	A2	4,277,178	7/1981	Cushing et al.		
	A3	4,306,808	12/1981	Vander Neut		
	A4	4,376,583	3/1983	Alford et al.		
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	A6	4,391,238 524	9/1983	Steigmeier et al.		
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	A11	4,589,773	5/1996	Ido et al.		

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							Translation	
	Document	Date	Country	Class	Subclass		Yes	No
	B1	065051A2	12/1981	Europe				
	B2	2-78936	3/1990	Japan			Yes	
	B3	2-87047	3/1990	Japan			Yes	
	B4	3-225939	10/1991	Japan			Yes	
	B5	6-34559	2/1994	Japan			Yes	

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C1	"Dynamic performance of a scanning X-Y stage for automated electron-beam inspection," D.J. Clark et al., <i>J. Vac. Sci. Technol. B</i> , Vol. 10, No. 6, Nov/Dec 1992, pp. 2638-2642
C2	"Inspection of Patterned Wafers: 0.35 μ m Design Rules and Beyond," J.R. Dralla et al., presented at Semicon Kansai Japan, 1994, pp. 1-8
C3	"Acoustooptic Scanners and Modulators," publication of Westinghouse Electric Corporation, Gottlieb, pp. 615-685

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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	A12	4,598,997	7/1986	Steigmeier et al.		
	A13	4,601,576	7/1986	Galbraith		
	A14	4,614,427	9/1986	Koizumi et al.		
	A15	4,650,983	3/1987	Suwa		
	A16	4,728,190	3/1988	Knollenberg		
	A17	4,740,708	4/1988	Batchelder		
	A18	4,748,333	5/1988	Mitzutani et al.		
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	A20	4,766,324	8/1988	Saadat et al.		
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						Yes	No
B6	62-153737	7/1987	Japan			Yes	
B7	62-274633	11/1987	Japan			Yes	
B8	63-73635	4/1988	Japan			Yes	
B9	62-128135	6/1987	Japan			Yes	
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C5	"Dual Sensor Technology for High Speed Detection of 0.1 Micron Defects," Alumont et al., <i>SPIE</i> , Vol. 1926 "Integrated Circuit Metrology, Inspection and Process Control VII," 1993, pp. 1-12
C6	"New Laser Scanning Techniques for Wafer Inspection," M. Nikoonahad et al. <i>SPIE</i> , Vol. 2638, February 1995, pp. 285-301

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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	A23	4,800,268	1/1989	Miyoshi et al.		
	A24	4,844,617	7/1989	Kelderman et al.		
	A25	4,864,123	9/1989	Mizutani et al.		
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					Yes No

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| C7 | "Scatterometers Improve Laser Mirrors," G. Valliant, TMA Technologies, Inc., <i>Photonics Spectra</i> , Vol. 25, Issue 8, August 1991, p. 100 |
| C8 | "Windowing effects on light scattering by sinusoidal surfaces," E. Marx et al., <i>SPIE</i> , Vol. 1995 Optical Scattering, 1993, pp. 2-14 |
| C9 | "A Light Scattering and Distribution Model for Scintillation Cameras," S. Rioux et al., <i>SPIE</i> , Vol. 1995 Optical Scattering, 1993, pp. 15-25 |

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	A42	5,166,516	11/1992	Kajimura			
	A43	5,168,386	12/1992	Galbraith			
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						Yes	No

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	A57	5,742,422	4/1998	Drake		
	A58	5,805,278	9/1998	Danko		

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C14	"Preparing Samples for Scattering Measurements - A Cleaning Study: Part 2, J. Brown, <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 80-91
C15	"Design review of an instrument to map low level hydrocarbon contamination," B. Swimley et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp.92-120
C16	"Design review of a high accuracy UV to near IR scatterometer," T. Schiff et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 121-130
C17	"Design review of a unique laser monostatic bidirectional reflectometer," Z. Gu et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 131-142
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C20	"Real-time detection of surface damage by direct assessment of the BRDF," H. Rothe et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 168-180
C21	"Microtopography investigations of optical surfaces and thin films by light scattering, optical profilometry, and atomic force microscopy," A. Duparré et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 181-192

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		Document	Date	Country	Class	Subclass	Translation		
							Yes	No	
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	C31	"BRDF Round Robin Test of ASTM E1392," T.A. Leonard et al., <i>SPIE</i> Vol. 1995 Optical Scattering, 1993, pp. 285-293							
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U.S. Patent Documents

*Examiner
InitialDocument
Number

Date

Name

Class

Subclass

Filing Date
If Appropriate

Foreign Patent Documents

Translation

Document

Date

Country

Class

Subclass

Yes

No

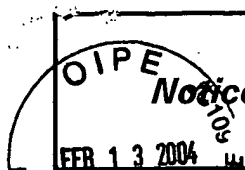
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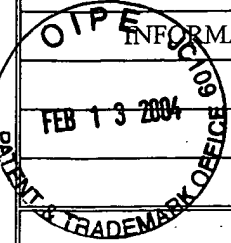
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				M-10575-2C US		09/760,558		
				Applicant(s)				
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